
What is Claimed is:

1. A method for purifying semiconductor waste gas comprising the step of:

5 injecting hot air to a waste gas outlet of a semiconductor gas abatement system so that the hot air blows into semiconductor waste gas exhausted from the waste gas outlet for catalyzing and decomposing harmful materials in the semiconductor waste gas.

10 2. The method for purifying semiconductor waste gas as claimed in claim 1, wherein the hot air generates from a hot air generator.

3. The method for purifying semiconductor waste gas as claimed in claim 2, wherein the hot air generator is installed in a head section of the semiconductor gas abatement system.

15 4. The method for purifying semiconductor waste gas as claimed in claim 2, wherein the hot air generator is installed on the semiconductor gas abatement system.

5. The method for purifying semiconductor waste gas as claimed in claim 2, wherein the hot air generator is installed outside of the semiconductor gas abatement system.

20 6. The method for purifying semiconductor waste gas as claimed in claim 5, wherein the hot air generator is connected to a hot air supply tube and the hot air is guided to the waste gas outlet in the semiconductor gas abatement system.

25 7. The method for purifying semiconductor waste gas as claimed in claim 6, wherein the hot air supply tube is installed on the head section of the semiconductor gas abatement system.

8. The method for purifying semiconductor waste gas as claimed in claim 6, wherein the hot air tube is installed in the semiconductor gas abatement system.